



Lab Works at Grenoble: Overview and Organization

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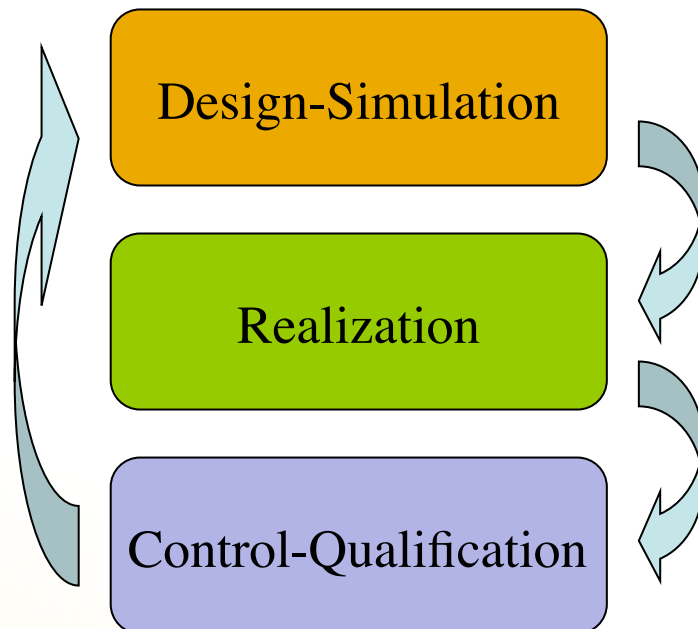


Outline

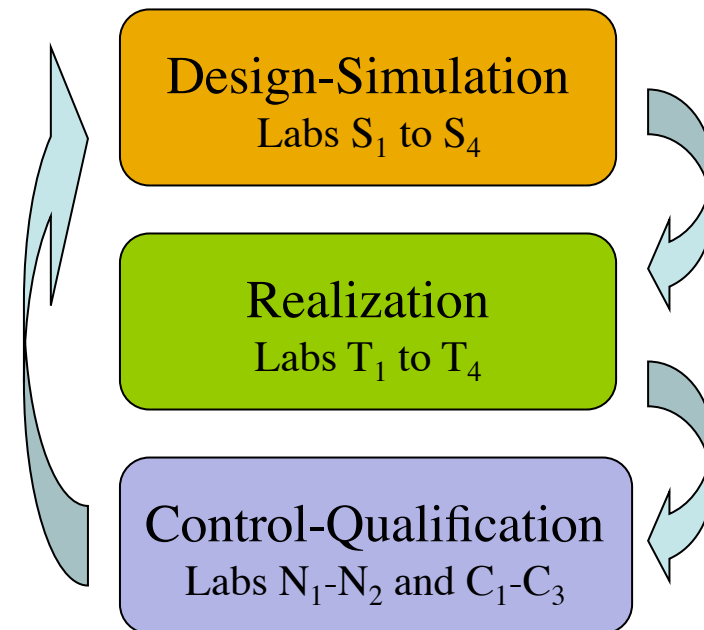
- Objectives
- Organization
 - Study logic
 - Breakdown structure
 - Schedule
 - Where? When?
- Evaluation

Labs Objectives

- Device manufacturing flow:

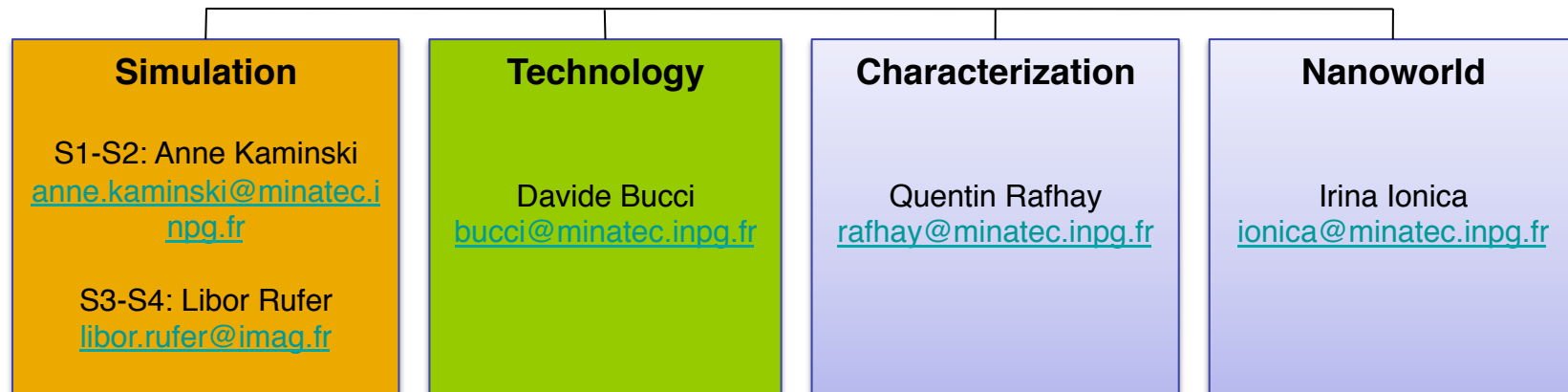


- Lab-work organization:



Organization

- Contacts:

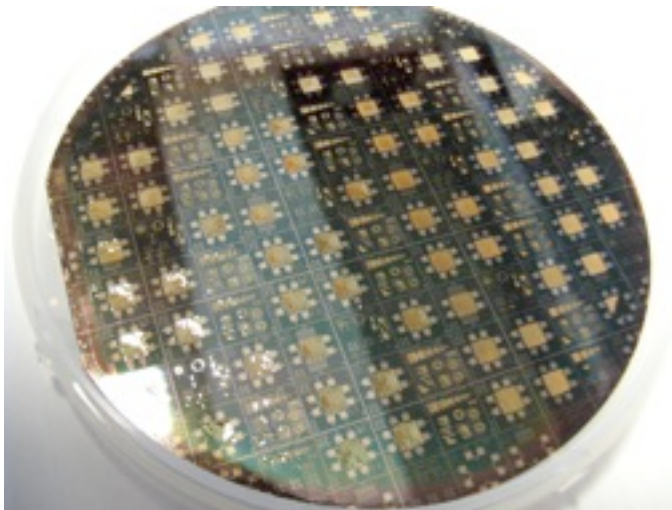


- Labs rules:

- Attendance to the labs is mandatory!
(unjustified absence \Leftrightarrow score reduction)
- Sessions start on time (8 AM or 13 PM)
- Technical staff rules...

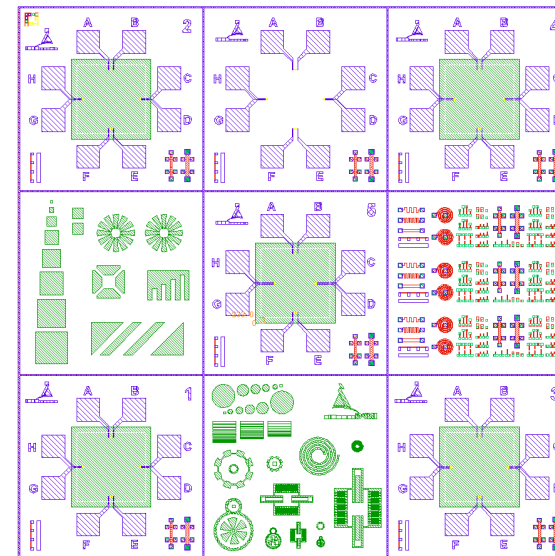
All for one chip, one chip for all

- Wafers:



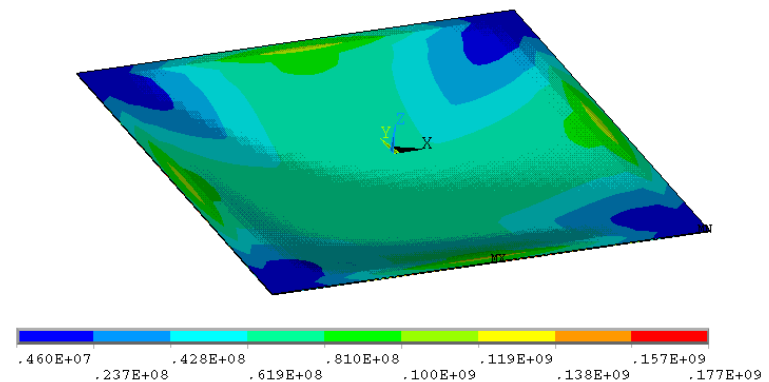
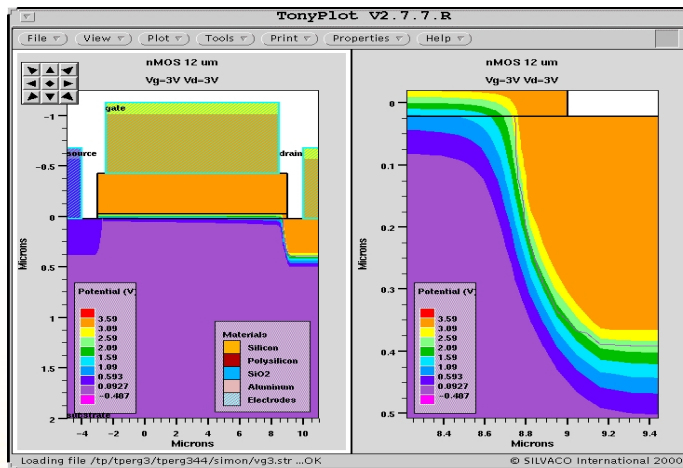
- 4-inches SOI or Si
- CMOS and MEMS devices

- Chip layout:



S₁-S₄: Simulation sessions

- S₁: technological sim.
 - Athena software
- S₂: electrical sim.
 - Atlas software
- S₃-S₄: electro-mechanical simulation
 - ANSYS software
 - Course L. Rufer (MEMS)



T₁-T₄: Clean-room sessions

- Work in a clean room:

- Dedicated suits



- Trousers and T-shirt
- Strict respect of the **safety procedures**
- Bring an USB key

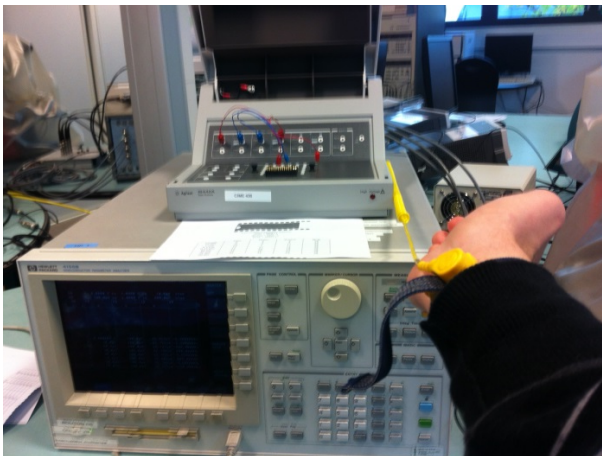
- MEMS-CMOS proc. flow:



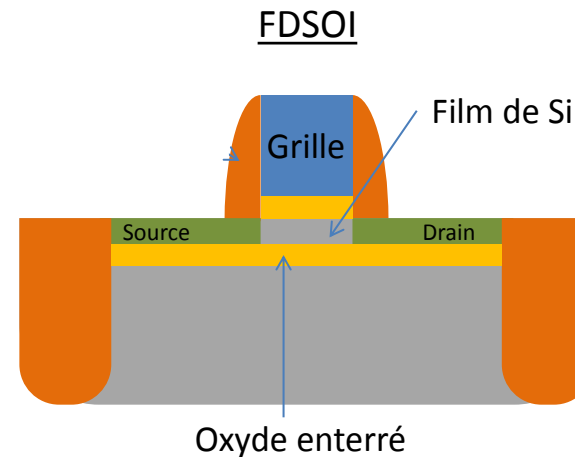
- Double-side photolithography, deep RIE, ion implantation, oxidation, etc...

C₁-C₃: Characterization sessions

- C₁₋₂: CMOS caract.
- C₃: FDSOI



Standard industrial measurements



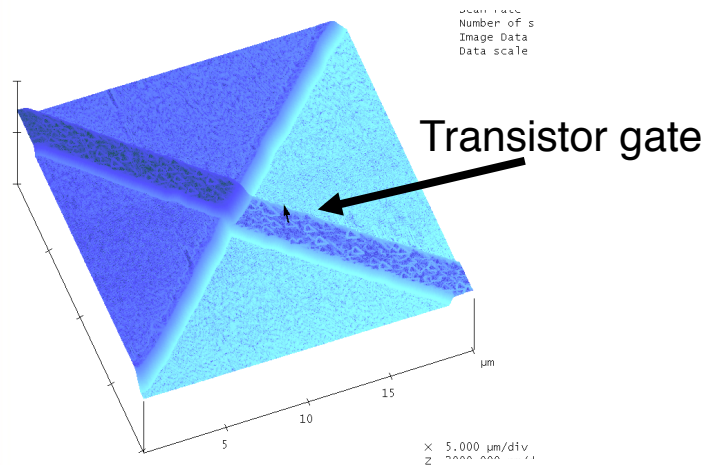
Advanced techniques



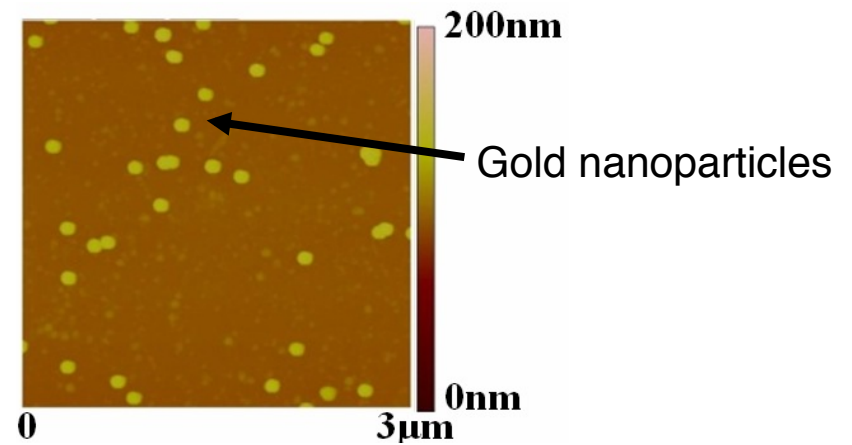
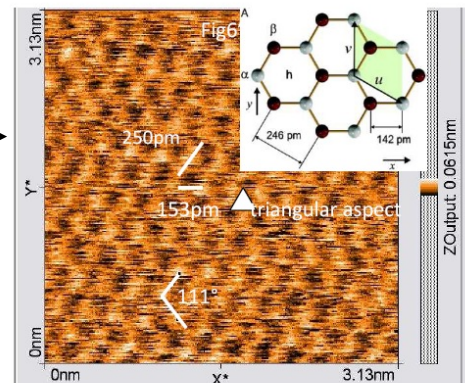
N₁-N₂: Nanoworld sessions

N₁: STM, contact mode AFM

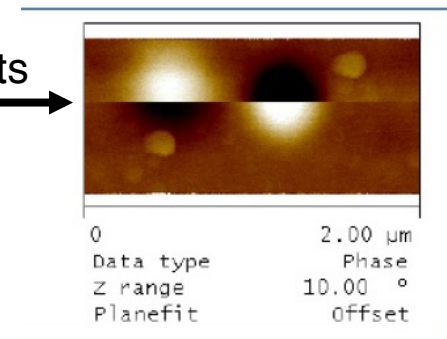
N₂: Tapping mode AFM, EFM



Graphite
atomic structure



Charging effects



Planning

			G1	G2	G3	G4	G5	G6	G7	G8	G9	G10
Wed	04/02/15	AM	S1	AK	S1	S1				N1	II	
Wed	04/02/15	PM	S2	AK	S2	S2		project		N2	II	
Thur	05/02/15	PM	S3	LR	S3	S3		project				project
Wed	11/02/15	AM	T1	DB	T1	QR	S1	AK	S1		N1	JCh
Wed	11/02/15	PM	T2	DB	T2	QR	project		project		N2	JCh
Mon	23/02/15	AM	S4	LR	S4	S4	S2	AK	S2	Bio1		project
Wed	25/02/15	AM	T3	DB	T3	QR	N1	JCh	S3	LR	S3	S1
Wed	25/02/15	PM	T4	DB	T4	QR	N2	JCh	S4	LR	S4	S2
Mon	02/03/15	PM	C1	LP	C2		project				Communication at work	
Wed	04/03/15	AM	project		T1	DB	T1	MB		N1	LB	S3
Wed	04/03/15	PM	C2	LP	C1	T2	DB	T2	MB	N2	XM	S4
Mon	09/03/15	PM			Communication at work					Bio2		project
Wed	11/03/15	AM	C3	IBA		T3	DB	T3	MB	N1	LB	project
Wed	11/03/15	PM		C3	IBA	T4	DB	T4	MB	N2	XM	project
Wed	18/03/15	AM	project		C1	LP	C2		T1	Aku	T1	AK
Wed	18/03/15	PM	project		C2	LP	C1		T2	Aku	T2	AK
Wed	25/03/15	AM			C3	MB			T3	Aku	T3	AK
Wed	25/03/15	PM	project			C3	MB	T4	Aku	T4	AK	Bio2
Wed	01/04/15	AM	project		project		C1	IBA	C2		T1	MB
Wed	01/04/15	PM		Communication at work		C2	IBA	C1		T2	MB	T2
Wed	08/04/15	AM	N1	SC			project	C3	MB		T3	T3
Wed	08/04/15	PM	N2	XM			project		C3	MB	T4	T4
Wed	22/04/15	AM							Communication at work		T1	MB
Wed	22/04/15	PM		Communication at work			project		C1	IBA	C2	T2
Wed	29/04/15	AM		Communication at work			project				T3	T3
Wed	29/04/15	PM				project			C2	MB	C1	T4
Wed	06/05/15	AM		Communication at work							C1	IBA
Wed	06/05/15	PM		N1	SC			Communication at work			C1	IBA
Tues	12/05/15	AM		N2	XM		project			C3	IBA	
Wed	13/05/15	AM	project			N1	SC		project		C3	IBA
Wed	13/05/15	PM	project			N2	XM		Communication at work		C3	IBA
Wed	20/05/15	AM							Communication at work			C3
Wed	20/05/15	PM										IBA
BULATS 14h00-16h00												

First session:
February 4, AM

Tight schedule!

Where and when?

- **S₁-S₄**: e. hall BCA-I building
- **T₁-T₄**: e. hall BCA-I building
- **N₁-N₂**: e. hall BCA-I building
- **C₁-C₃**: e. hall BCA-I building



ALL: 8 AM or 13 PM

Handouts

- Clean room (T1-T4)
(clean room paper)
 - Questions about the process flow
 - Process flow slides
 - Wafer page
- C, S and N:
(normal paper)
 - C1-C3
 - S1-S2
 - N1-N2

Evaluation

T, C, N: a single oral examination session in front of a jury (2 professors).

“Explain how you ensure that the rinsing of your samples is complete.
Does this method work equally well for acids, bases and solvents?”

Notes taken on the handouts are considered in the mark (laboratory notebook)

S: a single 3-5 pages report

Final mark = oral (T, C, N) 75% + report (S) 25%

Unjustified absence: -2 points on final mark



Evaluation and reporting

- Session reporting rules:
 - Fixed and communicated by each session professor.
- Reports (max 15 pages)
- S3-S4: course L. Rufer
- Evaluation:
 - For each session:
Reports and participation
Unjustified absence:
-2 points per 4h lab
- Final mark:

$$FM = \frac{4T_{1-4} + 2S_{1-2} + 3C_{1-3} + 2N_{1-2}}{11}$$

Reports

Groups of		Preparation	Deadline
T, C	4	Read the documents	2 weeks after the final session
S1-S2	2	Read the documents	2 weeks after the final session
N	2	Read the documents, do the calculations	At the end of each session

Conclusion

- Four categories of labs in CIME-MINATEC:
 - Simulation
 - Technology
 - Characterization
 - Nanoworld
- Complete
Micro-nanotech
process flow
- State-of-the-art tools and procedures
 - One contact person assigned per lab type
 - In case of problems, **warn us in time!**